

**AMENDMENTS TO THE CLAIMS**

The following is a complete, marked-up listing of revised claims with a status identifier in parenthesis, underlined text indicating insertions, and strike through and/or double-bracketed text indicating deletions.

**LISTING OF CLAIMS**

1.-21. (Cancelled).

22. (Previously Presented) A capacitor of a semiconductor device, the capacitor comprising:

a lower electrode;

an AHO((Al<sub>x</sub>,Hf<sub>1-x</sub>)O<sub>y</sub>) film formed on the lower electrode;

an upper electrode formed on the AHO film; and

a dielectric film having a dielectric constant that is higher than that of the AHO film between the upper electrode and the AHO film,

wherein the dielectric film is an HfO<sub>2</sub> layer, a ZrO<sub>2</sub> layer, or an STO layer, and

wherein the dielectric film is directly in contact with the upper electrode.

23. (Currently Amended) The capacitor of claim 22, further comprising an oxidation barrier film formed between the lower electrode and the AHO ~~layer~~film.

24.-37. (Cancelled).

\*\*\* END CLAIM LISTING \*\*\*